

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	3451	(118/715).CCLS.	US-PGPUB; USPAT	OR	OFF	2007/08/06 07:53
S2	1	10/783316	US-PGPUB; USPAT	OR	ON	2007/07/24 15:38
S3	20	("20030022507" "20030138562" "5250323" "5447847" "5447887" "5780360" "5817576" "6193813" "6218268" "6248410" "6309996" "6326297" "6355571" "6358844" "6365518" "6368948" "6429126" "6492266" "6537910" "6541374").PN.	US-PGPUB; USPAT	OR	ON	2007/07/20 17:43
S4	14	dichlorosilane adj3 liquid	US-PGPUB; USPAT	OR	ON	2007/07/21 08:34
S5	38	((advantage or benefit) same (three adj way adj valve)) and (semiconductor adj3 (manufactur\$3 or process\$3 or apparatus))	US-PGPUB; USPAT	OR	ON	2007/07/21 09:36
S6	17	(chemical adj vapor adj (deposition or growth)) and S5	US-PGPUB; USPAT	OR	ON	2007/07/21 09:37
S7	16	applied-material-inc.as.	US-PGPUB; USPAT	OR	ON	2007/07/22 11:26
S8	6132	applied-materials-inc.as.	US-PGPUB; USPAT	OR	ON	2007/07/22 11:25
S9	4925	( S7 S8 ) and deposition	US-PGPUB; USPAT	OR	ON	2007/07/22 11:26
S10	2904	S9 and CVD	US-PGPUB; USPAT	OR	ON	2007/07/22 11:26
S11	2	("5445676" "6185839").PN.	US-PGPUB; USPAT	OR	ON	2007/07/22 12:01
S12	51	gas adj distribution adj face adj plate	US-PGPUB; USPAT	OR	ON	2007/07/24 15:59
S13	15484	injection adj valve	US-PGPUB; USPAT	OR	ON	2007/07/24 15:59
S14	203	semiconductor adj (manufactur\$3 or process\$3 or apparatus or equipment) and S13	US-PGPUB; USPAT	OR	ON	2007/07/24 16:02
S15	35	(liquid adj flow adj meter) same (mass adj flow adj control\$3)	US-PGPUB; USPAT	OR	ON	2007/07/24 16:02
S16	19	(liquid adj flow adj meter) with (mass adj flow adj control\$3)	US-PGPUB; USPAT	OR	ON	2007/07/24 16:02